

- A) remedies for latch-up? Explain in detail with necessary circuit diagrams and curve.
- B) In CMOS inverter, if $V_{DD} = 1.5V$, $V_{tn} = 0.4V$, $V_{tp} = -0.4V$, $K_n = 200 \mu A/V^2$ and $K_p = 100 \mu A/V^2$: (10)
- i) The peak current of $35 \mu A$ occurs at $0.6V$. What is $(W/L)_n$?
- ii) What is the $(W/L)_p$?
- 3) With precise figures explain the different steps involved in the fabrication of NMOS transistor. What is the advantage of the self-aligned process? (10)
- A)
- B) Draw the circuit, stick diagram and layout of two input NAND gate using NMOS design style. (10)
- 4) Explain the working and draw transfer characteristic of NMOS inverter with (10)
- A)
- i) Resistor pull-up
- ii) Depletion mode transistor pull-up
- iii) Enhancement mode pull-up
- B) Discuss the operation of 6T SRAM in detail. (10)
- 5) Explain different scaling models. Discuss the effect of different scaling on following parameters: (10)
- A)
- [i] Gate oxide capacitance C_g [ii] Channel resistance R_{on}
- [iii] Gate delay T_d
- B) Implement Boolean function $F = (x + y)[z + (w.t)(z + x)]$ using (10)
- i) CMOS logic
- ii) NMOS logic
- iii) pseudo NMOS logic.
- 6) Given that $1/C_g = 0.01 \text{ pF}$. (10)
- A) Find the optimal number of NMOS inverters to be cascaded so as to drive an off-chip capacitive load of 0.54 pF such that the total delay is minimized. Give the cascaded structure, clearly showing the L:W ratio. Show the delay T_d across each inverter stage and hence calculate the overall delay.
- B) An enhancement type NMOS has $V_t = 0.8V$ and $\mu_n C_{ox} = 20 \mu A/V^2$ (10)
- i) Find (W/L) for $V_G = 2.8V$, $V_D = 5V$, $V_S = 1V$ and $I_D = 0.24mA$.
- ii) Calculate I_D for $V_G = 5V$, $V_D = 4V$, $V_S = 2V$ for same (W/L) as in part (i)

- 7) What is a cross-bar switch? Bring out the differences between barrel shifter and cross-bar switch. Give the circuit implementation and the stick notation of 4X4 barrel shifter. (10)
- A)
- B) Give hardware implementation and draw stick diagram for storing following 4-bit words using NMOS ROM structure. (10)
- word1: 0101; word2: 0010 ; word3: 1001 ; word4: 0110
- 8) Calculate the effective capacitance for the given multi-layer structure in Figure 8A for 5 μm process. Relative Capacitance value for metal1= 0.075, polysilicon=0.1 and Gate-to-channel = 1.0. (10)
- A)

Figure 8A

- B) Discuss cascaded inverters as drivers for driving large capacitive loads and derive the necessary expressions. (10)